



Correction to: Towards achieving nanofinish on silicon (Si) wafer by μ -wire electro-discharge machining

Sams Jarin¹ · Tanveer Saleh¹  · Asan G. A. Muthalif^{1,2} · Mohammad Yeakub Ali¹ · Moinul Bhuiyan³

Published online: 4 October 2018
© Springer-Verlag London Ltd., part of Springer Nature 2018

Correction to: Int J Adv Manuf Technol

<https://doi.org/10.1007/s00170-018-2692-4>

The authors would like to publish an Acknowledgement section.

Acknowledgments This work was supported by the Fundamental Research Grant (FRGS/1/2014/TK01/UIAM/02/2) sponsored by the Ministry of Higher Education Malaysia. Authors also acknowledge the research support provided by the International Islamic University Malaysia.

The online version of the original article can be found at <https://doi.org/10.1007/s00170-018-2692-4>

✉ Tanveer Saleh
tanveers@iium.edu.my

- ¹ Faculty of Engineering, International Islamic University Malaysia, Kuala Lumpur, Wilayah Persekutuan, Malaysia
- ² Department of Mechanical and Industrial Engineering College of Engineering, Qatar University, Building B09 - near to QU Mosque, P.O. Box 2713, Doha, Qatar
- ³ School of Science and Engineering, International University of Scholars, Dhaka, Bangladesh